AMENDMENTS TO THE DRAWINGS

The attached sheets of drawings include changes to Figs. 5 and 6. These sheets, which includes Figs. 5 and 6, replaces the original sheets including Figs. 5 and 6. The following changes have been made to Figs. 5 and 6. In Fig. 5 reference number 423 has been added. In Fig. 6 reference number 523 has been added.

Attachment:

Replacement sheet

Annotated sheet showing changes

REMARKS

At the outset, the Examiner is thanked for the thorough review and consideration of the pending application. The final Office Action dated March 9, 2006, has been received and its contents carefully reviewed.

Claims 1-8 and 11-19 are rejected and claim 14 is objected to by the Examiner. Claims 9 and 10 are canceled. Claims 1 and 14 have been amended. Claims 1-8 and 11-19 remain pending in this application.

In the Office Action, claims 1-5, 8 and 11-13 are rejected under 35 U.S.C. § 102(b) as being anticipated by U.S. Patent No. 6,236,163 to Maishev et al. (hereinafter "Maishev"). Claim 6 is rejected under 35 U.S.C. § 102(b) as being anticipated by U.S. Patent No. 4,449,051 to Berkowitz (hereinafter "Berkowitz"). Claims 7 and 14-19 are rejected under 35 U.S.C. § 103(a) as being unpatentable over Maishev in view of U.S. Patent No. 5,770,826 to Chaudhari et al. (hereinafter "Chaudhari").

Claim 14 has been amended as recommended by the Examiner in order to overcome the objection.

The rejection of claims 1-5, 8 and 11-13 is respectfully traversed and reconsideration is requested. Claims 1-5, 8 and 11-13 are allowable over the cited references in that each of these claims recites a combination of elements including, for example, "an ion beam source that is a predetermined distance from the substrate and that irradiates the substrate with an ion beam along the ion beam path, wherein the ion beam is discharged from the ion beam source with an incidence angle with respect to the ion beam source that is greater than about 0° and the emitting surface of the ion beam source is inclined to be substantially parallel with the substrate and wherein irradiated ions follow paths that are substantially parallel and straight." Maishev does not teach or suggest at least this feature of the claimed invention.

In Figure 5 of Maishev as cited by the Examiner, the ion beam paths diverge after they are emitted. Therefore, the irradiated ions do not "follow paths that are substantially parallel and straight" as required by the present invention. Accordingly, claims 1-6, 8 and 11-13 are allowable over Maishev.

Further, claim 7 which depends from claim 1 is allowable over Maishev as well. The Examiner also cited Chaudhari against claim 7, and Chaudhari fails to cure the deficiencies of claim Maishev, therefore claim 7 is allowable over Maishev and Chaudhari, singly or in combination.

Regarding the rejection of claim 6, the Applicants question whether the Examiner intended to reject claims 1 and 2 as well as being anticipated by Berkowitz as claim 6 depends from claims 1 and 2. The rejection of claim 6, and if need be claim 1, is respectfully traversed and reconsideration is requested. Claim 6 is allowable over the cited references in that each of these claims recites a combination of elements including, for example, "an ion beam source that is a predetermined distance from the substrate and that irradiates the substrate with an ion beam along the ion beam path, wherein the ion beam is discharged from the ion beam source with an incidence angle with respect to the ion beam source that is greater than about 0° and the emitting surface of the ion beam source is inclined to be substantially parallel with the substrate and wherein irradiated ions follow paths that are substantially parallel and straight." Berkowitz does not teach or suggest at least this feature of the claimed invention.

In Berkowitz the ion beams are emitted by an ion source 8 and then are bent to finally reach item 36. Therefore, the irradiated ions do not "follow paths that are substantially parallel and straight." Accordingly, claim 6 is allowable over Berkowitz.

The rejection of claims and 14-19 is respectfully traversed and reconsideration is requested. Claims 14-19 are allowable over the cited references in that each of these claims recites a combination of elements including, for example, "producing ion beams to simultaneously irradiate the whole substrate with ions, wherein the ion beams strike the substrate with the same incidence angle and energy across the substrate, and wherein the ion beams all travel substantially the same distance and the incidence angle is greater than about 0° and wherein irradiated ions follow paths that are substantially parallel and straight." None of the cited references including the Maishev and Chaudhari, singly or in combination, teaches or suggests at least this feature of the claimed invention. Claims 14-19 are allowable over Maishev. Accordingly, claims 14-19 are allowable over Maishev and Chaudhari.

Docket No. 8733.977.00

Applicants believe the foregoing amendments place the application in condition for allowance and early, favorable action is respectfully solicited.

If for any reason the Examiner finds the application other than in condition for allowance, the Examiner is requested to call the undersigned attorney at (202) 496-7500 to discuss the steps necessary for placing the application in condition for allowance. All correspondence should continue to be sent to the below-listed address.

If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. § 1.136, and any additional fees required under 37 C.F.R. § 1.136 for any necessary extension of time, or any other fees required to complete the filing of this response, may be charged to Deposit Account No. 50-0911. Please credit any overpayment to deposit Account No. 50-0911. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

Dated: July 7, 2006

Eric J. Nuss

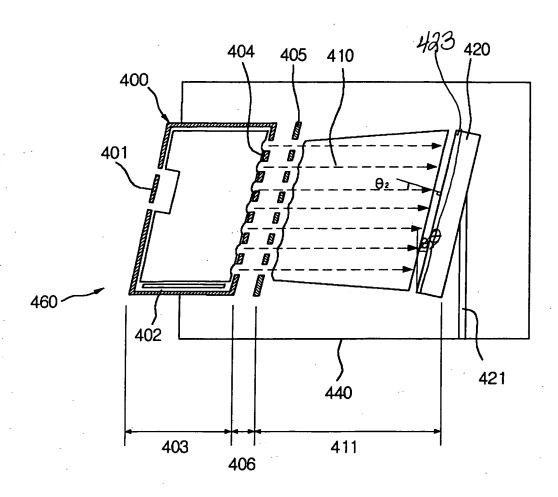
Registration No. 40,106

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Attachments

Title: ION BEAM IRRADIATION DEVICE Inventors: Yun Bok LEE et al. App No. 10/736,677; Filed: December 17, 2003 Annotated Sheet 1 of 2

Fig.5





Title: ION BEAM IRRADIATION DEVICE Inventors: Yun Bok LEE et al. App No. 10/736,677; Filed: December 17, 2003 Annotated Sheet 2 of 2

Fig.6

